

PATENT

Case Docket No. ASMEX.236A Date: September 30, 2002

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In re application of: Raaijmakers et al. 09/658,784 App. No. September 11, 2000 Filed For LOADLOCK WITH INTEGRATED PRE-CLEAN

CHAMBER

Examiner

R. Zervigon

Art Unit

1763

UNITED STATES PATENT AND TRADEMARK OFFICE BOX AF P.O. Box 2327 Arlington, VA 22202

Sir:

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated as shown below:

CLAIMS REMAINING AFTER **AMENDMENT** I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: United States Patent and Trademark Office, P.O. Box 2327, Arlington, VA 22202, on

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65	= 9 ×	\$18	= \$162

Total Claims 74 Independent Claims 9 = 0\$84 = \$0Time Extension Fee \$0

CLAIMS AS FILED

TOTAL ADDITIONAL FEE

FOR THIS AMENDMENT

\$162

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Gordon H. Olson

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	· :	Raaijmakers et al.) Group Art Unit: 1763	#130.14
Appl. No.	:.	09/658,784		10/8/2
Filed	:•	September 11, 2000	? RE	o.
For	:	LOADLOCK WITH INTEGRATED PRE-CLEAN CHAMBER)	CEIVED 27 2002
Examiner		R. Zervigon))	100
	AN	MENDMENT AFTER FINAL UNDER	2.37 C.F.R. § 1.116	and to be
Assistant Cor Washington,		ner for Patents 0231	A	1310

Dear Sir:

That Jeuga,

In response to the Final Office Action mailed July 21, 2002, Applicant respectfully submits the following amendments and comments in connection with the above-captioned application.

IN THE SPECIFICATION:

Please amend the paragraph starting at page 16, line 13, as follows:

The elevator mechanism moves the second elevator plate 402 between an outside position where the wafer carrier 50 is located outside the load lock 400 (see Figure 11A) and a sealed position where the wafer carrier 50 is located within the load lock 400 (see Figure 11B). In this sealed position, the second elevator plate 402 substantially closes the load lock port 34. Preferably, the second elevator plate 402 includes a sealing portion 406, which cooperates with a corresponding sealing portion 408 formed on the load lock 400 to substantially seal the load lock port 34.

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